

Atty Dkt. No.
33082M065

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Masahiko MATSUDO, et al.

Serial No.: 09/757,583

Filed : January 11, 2001

For : METHOD FOR DEPOSITING TUNGSTEN SILICIDE FILM AND METHOD
FOR PREPARING GATE ELECTRODE/WIRING

Group Art Unit: Unassigned

Examiner: Unassigned



INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Pursuant to the duty of disclosure under 37 C.F.R. 1.56, Applicants are enclosing an Information Disclosure Citation Form (PTO-1449) and a copy of each of the documents cited therein.

Applicants have the following comments concerning the documents cited by this Statement.

U.S. Patent Application No. 09/385,848 (assigned to Tokyo Electron Limited and filed on August 30, 1999) discloses a method comprising a step of forming a silicon-rich tungsten-silicide layer from a process gas including phosphorus. It also discloses forming a tungsten-rich tungsten-silicide layer on the silicon-rich tungsten-silicide layer.

U.S. Patent Application No. 09/023,712 (assigned to Tokyo Electron Limited and filed on February 13, 1998) discloses a film layer structure. It aims to avoid a nonuniform dissipation of impurities to the upper tungsten-silicide layer from the lower polycrystal silicon layer.



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PATENT TRADEMARK OFFICE

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Applicants understand European Patent Laid-Open No. EP0785574 A2 (Application No. 97300079.7 issued on August 1, 1997) to disclose a method that comprises a step of forming a first tungsten-silicide layer from SiH_4 on a doped silicon layer and a step of forming a second tungsten-silicide layer from DCS.

It is respectfully requested that the cited documents be considered by the Examiner in the above-identified patent application and that the cited documents be made officially of record therein. It is further requested that a listing of the same appear on the face of any patent which may issue from this application.

This Information Disclosure Statement is being filed within three months of the filing date of the present application, and therefore it is believed that no fees are due under 37 C.F.R. Section 1.97(i).

Respectfully submitted,

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